HS Code	Product Description	Base Rate	Year 1	Year 2	Year 3	Year 4	Year 5	Year 6	Year 7	Year 8	Year 9	Year 10	Year 11	Year 12	Year 13	Year 14	Year 15	Year 16	Year 17	Year 18	Year 19	Year 20 and Subsequent Years
8486.20.39.00	- - - Other	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
	- - Lithography equipment:																					
8486.20.41.00	- - - Direct write-on-wafer apparatus	15%	13%	13%	11%	11%	10%	10%	8%	8%	6%	6%	4%	4%	2%	2%	0%	0%	0%	0%	0%	0%
8486.20.42.00	- - - Step and repeat aligners	15%	13%	13%	11%	11%	10%	10%	8%	8%	6%	6%	4%	4%	2%	2%	0%	0%	0%	0%	0%	0%
8486.20.49.00	- - - Other	15%	13%	13%	11%	11%	10%	10%	8%	8%	6%	6%	4%	4%	2%	2%	0%	0%	0%	0%	0%	0%
	- - Equipment for developing exposed wafers:																					
8486.20.51.00	- - - Dicing machines for scribing or scoring semiconductor wafers	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.20.59.00	- - - Other	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
	- - Other:																					
8486.20.91.00	- - - Lasercutters for cutting contacting tracks in semiconductor production by laser beam	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.20.92.00	- - - Machines for bending, folding and straightening semiconductor leads	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.20.93.00	- - - Resistance heated furnaces and ovens for the manufacture of semiconductor devices on semiconductor wafers	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.20.94.00	- - - Inductance or dielectric furnaces and ovens for the manufacture of semiconductor devices on semiconductor wafers	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.20.95.00	- - - Automated machines for the placement or the removal of components or contact elements on semiconductor materials	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.20.99.00	- - - Other	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.30	- Machines and apparatus for the manufacture of flat panel displays:																					
8486.30.10.00	- - Apparatus for dry etching patterns on flat panel display substrates	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.30.20.00	- - Apparatus for wet etching, developing, stripping or cleaning flat panel displays	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.30.30.00	- - Chemical vapour deposition apparatus for flat panel display production; spinners for coating photosensitive emulsions on flat panel display substrates; apparatus for physical deposition on flat panel display substrates	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.30.90.00	- - Other	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.40	- Machines and apparatus specified in Note 9 (C) to this Chapter:																					
8486.40.10.00	- - Focused ion beam milling machines to produce or repair masks and reticles for patterns on semiconductor devices	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.40.20.00	- - Die attach apparatus, tape automated bonders, wire bonders and encapsulation equipment for the assembly of semiconductors; automated machines for transport, handling and storage of semiconductor wafers, wafer cassettes, wafer boxes and other materials for semiconductor devices	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.40.30.00	- - Moulds for manufacture of semiconductor devices	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.40.40.00	- - Optical stereoscopic microscopes fitted with equipment specifically designed for the handling and transport of semiconductor wafers or reticles	3%	3%	3%	2%	2%	2%	2%	2%	2%	2%	2%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%
8486.40.50.00	- - Photomicrographic microscopes fitted with equipment specifically designed for the handling and transport of semiconductor wafers or reticles	3%	3%	3%	2%	2%	2%	2%	2%	2%	2%	2%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%
8486.40.60.00	- - Electron beam microscopes fitted with equipment specifically designed for the handling and transport of semiconductor wafers or reticles	3%	3%	3%	2%	2%	2%	2%	2%	2%	2%	2%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%
8486.40.70.00	- - Pattern generating apparatus of a kind used for producing masks or reticles from photoresist coated substrates	2%	2%	2%	2%	2%	2%	2%	2%	2%	2%	2%	2%	2%	0%	0%	0%	0%	0%	0%	0%	0%
8486.40.90.00	- - Other	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.90	- Parts and accessories:																					
	- - Of machines and apparatus for the manufacture of boules or wafers:																					
8486.90.11.00	- - - Of apparatus for rapid heating of semiconductor wafers	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.90.12.00	- - - Of spin dryers for semiconductor wafer processing	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%

HS Code	Product Description	Base Rate	Year 1	Year 2	Year 3	Year 4	Year 5	Year 6	Year 7	Year 8	Year 9	Year 10	Year 11	Year 12	Year 13	Year 14	Year 15	Year 16	Year 17	Year 18	Year 19	Year 20 and Subsequent Years
8486.90.13.00	- - - Of machines for working any material by removal of material, by laser or other light or photon beam in the production of semiconductor wafers	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
	- - - Of machines for sawing monocrystal semiconductor boules into slices, or wafers into chips:																					
8486.90.14.00	- - - - Tool holders and self-opening dieheads; work holders; dividing heads and other special attachments for machine tools	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.90.15.00	- - - - Other	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.90.16.00	- - - Of grinding, polishing and lapping machines for processing of semiconductor wafers	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.90.17.00	- - - Of apparatus for growing or pulling monocrystal semiconductor boules	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.90.19.00	- - - Other	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
	- - Of machines and apparatus for the manufacture of semiconductor devices or of electronic integrated circuits:																					
8486.90.21.00	- - - Of chemical vapour deposition apparatus for semiconductor production	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.90.22.00	- - - Of epitaxial deposition machines for semiconductor wafers; of spinners for coating photographic emulsions on semiconductor wafers	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.90.23.00	- - - Of ion implanters for doping semiconductor materials; of apparatus for physical deposition by sputtering on semiconductor wafers; of physical deposition apparatus for semiconductor production; of direct write-on-wafer apparatus, step and repeat aligners and other lithography equipment	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
	- - - Of spraying appliances for etching, stripping or cleaning semiconductor wafers; of apparatus for wet etching, developing, stripping or cleaning semiconductor wafers; of dry-etching patterns on semiconductor materials:																					
8486.90.24.00	- - - - Tool holders and self-opening dieheads; work holders; dividing heads and other special attachments for machine tools	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.90.25.00	- - - - Other	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
	- - - Of dicing machines for scribing or scoring semiconductor wafers; of lasercutters for cutting tracks in semiconductor production by laser beam; of machines for bending, folding and straightening semiconductor leads:																					
8486.90.26.00	- - - - Tool holders and self-opening dieheads; workholders; dividing heads and other special attachments for machine tools	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.90.27.00	- - - - Other	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.90.28.00	- - - Of resistance heated furnaces and ovens for the manufacture of semiconductor devices on semiconductor wafers; of inductance or dielectric furnaces and ovens for the manufacture of semiconductor devices on semiconductor wafers	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.90.29.00	- - - Other	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
	- - Of machines and apparatus for the manufacture of flat panel displays:																					
8486.90.31.00	- - - Of apparatus for dry etching patterns on flat panel display substrates	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
	- - - Of apparatus for wet etching, developing, stripping or cleaning flat panel displays:																					
8486.90.32.00	- - - - Tool holders and self-opening dieheads; work holders; dividing heads and other special attachments for machine tools	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.90.33.00	- - - - Other	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%
8486.90.34.00	- - - Of chemical vapour deposition apparatus for flat panel display production	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	1%	0%	0%	0%	0%	0%	0%	0%	0%